

1. A semiconductor manufacturing apparatus comprising:

recording means for recording as predetermined data information of an operation to be executed by said main unit;

display means located remotely from said main unit and for displaying said simulated result.

3. A program for a semiconductor manufacturing apparatus comprising the steps of:

receiving from a supplier of supplying information of an operation to be executed by the semicon-

ductor manufacturing apparatus for processing raw materials and forming a semiconductor as predetermined data said data through communicating means;

displaying a simulated result supplied by operating means for operating the operation of said semiconductor manufacturing apparatus and simulating said operation by said data; and

transmitting said result to said supplier.

4. An operating system for a semiconductor manufacturing apparatus comprising:

means for receiving from a supplier of supplying information of an operation to be executed by the semiconductor manufacturing apparatus for processing raw materials and forming a semiconductor as predetermined data said data through communicating means;

display means for displaying a simulated result supplied by operating means for operating the operation of said semiconductor manufacturing apparatus and simulating said operation by using said data; and

wherein said data is received in response to a request given from a user of said semiconductor manufacturing apparatus and a diagnosed result of said semiconductor manufacturing apparatus based on said simulated result is supplied to the user of said semiconductor manufacturing apparatus.

5. A semiconductor manufacturing apparatus as claimed in claim 1, wherein said data includes the

information at a time when an abnormality takes place in said semiconductor manufacturing apparatus and said operating means simulates the operation in which said abnormality took place.

6. A diagnosis apparatus of a semiconductor manufacturing apparatus as claimed in claim 2, wherein said data includes information at a time when an abnormality takes place in said semiconductor manufacturing apparatus and said operating means simulates the operation in which said abnormality took place.

7. A program for a semiconductor manufacturing apparatus as claimed in claim 3, wherein said data includes information at a time when an abnormality takes place in said semiconductor manufacturing apparatus and said operating means simulates the operation in which said abnormality took place.

8. An operating system for a semiconductor manufacturing apparatus as claimed in claim 4, wherein said data includes information at a time when an abnormality takes place in said semiconductor manufacturing apparatus and said operating means simulates the operation in which said abnormality took place.

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